

Correction

# Correction: Design and Simulation of a Wireless SAW–Pirani Sensor with Extended Range and Sensitivity

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Received: 26 June 2019; Accepted: 18 July 2019; Published: 23 July 2019



The authors wish to make the following erratum to Reference [1]:

The Table 2 below contained false reference numbers. The references were corrected. The corrected references are also available below.

The authors would like to apologize for any inconvenience caused to the readers by these changes.

**Table 2.** Detection principles and pressure ranges of micro-electro-mechanical system (MEMS) Pirani gauges.

Researcher	Type of Gauge	Pressure Range (Pa)
Van Herwaarden and Sarro, 1988 [9]	Heated cantilever combined with thermopile	0.13–13,300
Völklein and Schnelle, 1991 [10]	Heated resistor combined with thermopile	0.13–10
Piotto et al., 2016 [11]	Heated resistor with thermopile	0.3–10 <sup>5</sup>
Mastrangelo and Muller, 1991 [12]	Microbridge	10–10,000
Swart et al., 1994 [13]	Microbridge	13–1.33 × 10 <sup>5</sup>
Chae et al., 2004 [14]	Microbridge	2.6–267
Moelders et al., 2004 [15]	Microbridge	1.33–133
Doms et al., 2005 [16]	Microbridge	100–10 <sup>5</sup>
Stark et al., 2005 [17]	Microbridge	1.33–10 <sup>6</sup>
Mitchell et al., 2008 [18]	Microbridge	1.33–10 <sup>5</sup>
Khosraviani and Leung, 2009 [19]	Microbridge	13.3–10 <sup>6</sup>
Li et al., 2009 [20]	Microbridge	10.6–26,665
Jiang et al., 2010 [21]	Microbridge	0.1–1,000
Chen, 2012 [22]	Microbridge	133–1.33 × 10 <sup>5</sup>
Puers et al., 2002 [23]	Microbridge	100–10 <sup>7</sup>
Moutaouekkil et al., 2015 [24]	Microbridge	1,000–10 <sup>5</sup>

Table 2. Cont.

Researcher	Type of Gauge	Pressure Range (Pa)
Mailly et al., 2009 [25]	Microbridge	20–20,000
Robinson et al., 1992 [26]	Resistor on dielectric membrane	10–13,300
Paul et al., 1994 [27]	Resistor on dielectric membrane	100–10 <sup>5</sup>
Weng and Shie, 1994 [5]	Resistor on dielectric membrane	1.33 × 10 <sup>-5</sup> –133
Shie et al., 1995 [28]	Resistor on dielectric membrane	13.3–1.33 × 10 <sup>7</sup>
De Jong et al., 2003 [29]	Resistor on dielectric membrane	10–20,000
Zhang et al., 2006 [30]	Resistor on dielectric membrane	10–10 <sup>5</sup>
Völklein et al., 2013 [3]	Resistor on dielectric membrane	1.33 × 10 <sup>-4</sup> –1332
Grau et al., 2014 [6]	Resistor on dielectric membrane	0.13–10 <sup>5</sup>
Xiao et al., 2011 [7]	Resistor on dielectric membrane	1–1,000
Takashima et al., 2008 [31]	Resistor on dielectric membrane	0.002–10 <sup>5</sup>
Jeon et al., 2016 [32]	Resistor on dielectric membrane	0.013–10 <sup>5</sup>
Paul and Baltes, 1995 [33]	Resistor on dielectric membrane	100–10 <sup>6</sup>
Wenzel and Bak, 1998 [34]	Resistor on diaphragm	10–10 <sup>5</sup>
Qiu et al., 2009 [35]	Metallic wire	1–100
Brun et al., 2012 [36]	Silicon nanowire	50–10 <sup>5</sup>
Ghouila-Houri et al., 2017 [37]	Microwire	10,000–8 × 10 <sup>5</sup>
Schelcher et al., 2011 [38]	Ni-microbeam	3.3–10 <sup>5</sup>
Wang et al., 2010 [39]	Microplate	0.1–10 <sup>5</sup>
Santagata et al., 2011 [40]	Tube-shaped	0.133–1.33 × 10 <sup>5</sup>
Mercier et al., 2012 [41]	Cr/Au-resistor on LiNbO <sub>3</sub> -substrate (SAW device)	0.001–10 <sup>5</sup>

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